

LIGHT COUPLING IN QUANTUM WELL INFRARED PHOTODETECTORS



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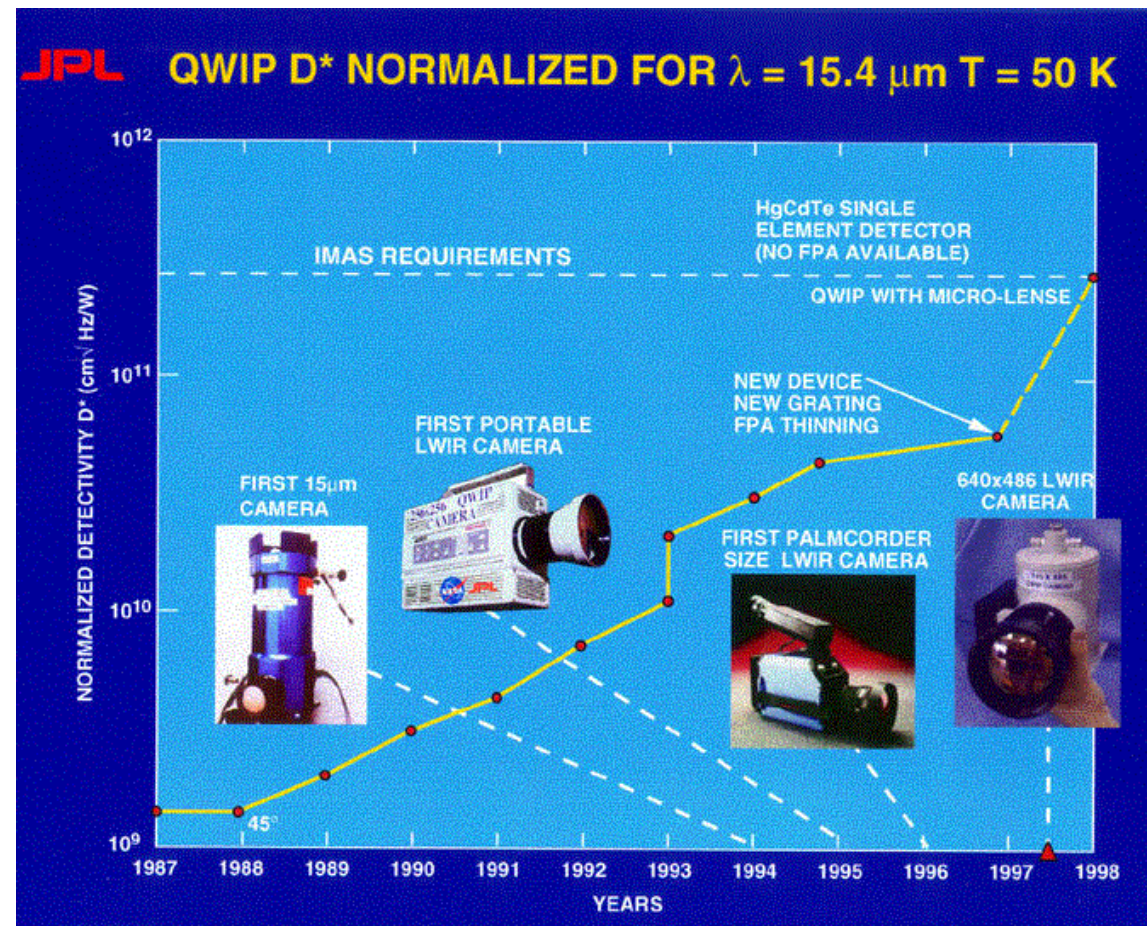
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Overview

Quantum Well Infrared Photodetectors: roadmap



Sarath Gunapala et al., JPL

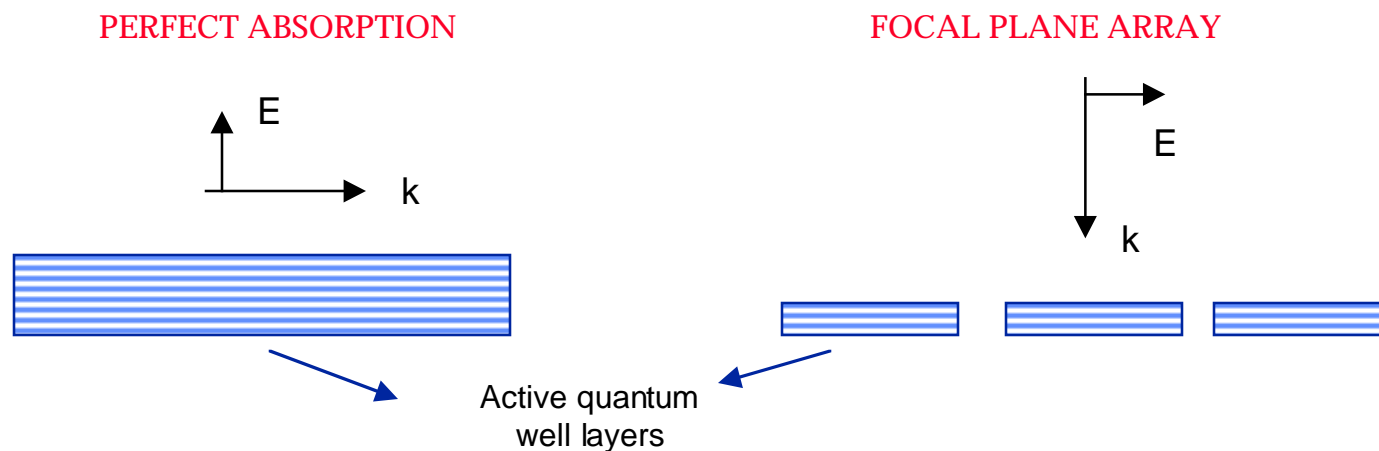
Light Coupling and Absorption

Energy Absorption in QWIPs

- Electric field must be perpendicular to quantum well layers

» *But ...*

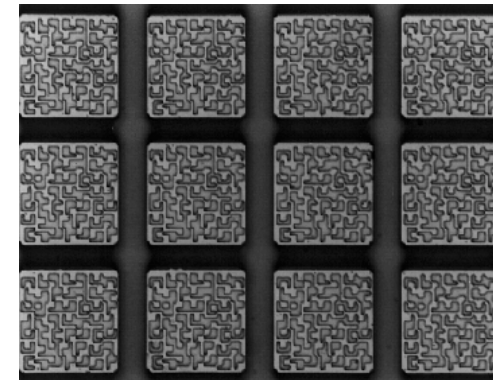
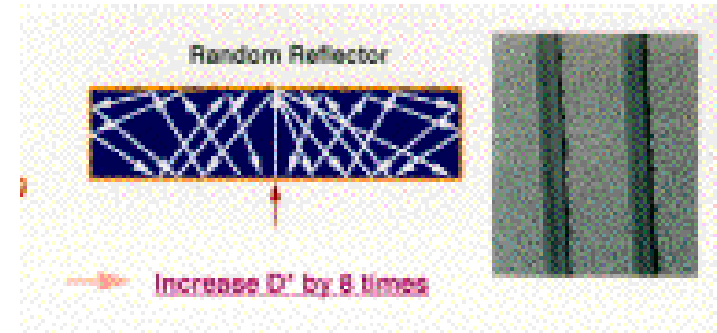
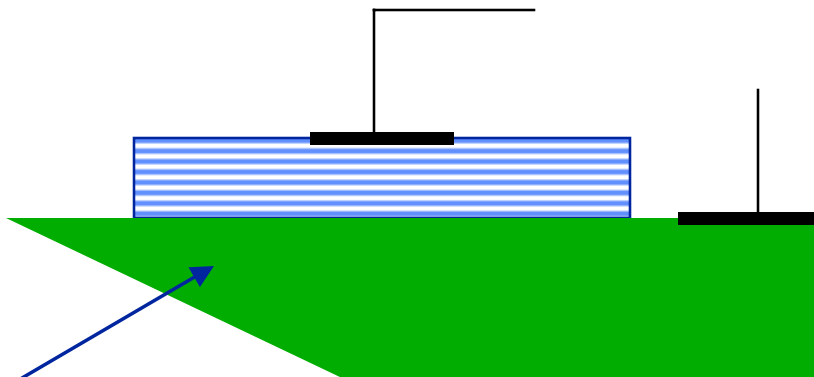
- Focal plane arrays require direction of propagation to be perpendicular to quantum well layers



Historically ...

Random surface scatterer

Standard 45 degree edge detector



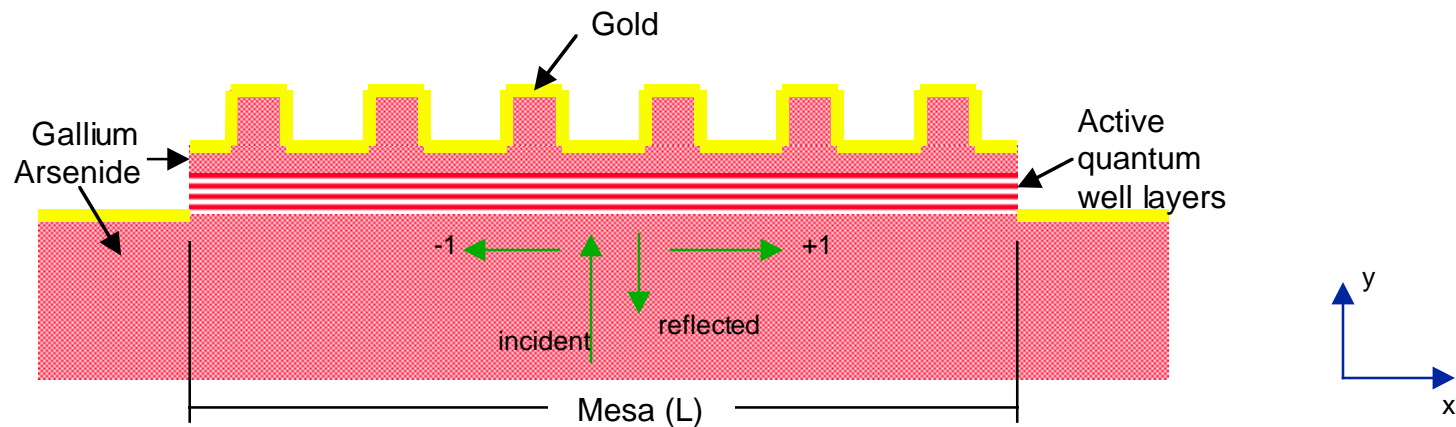
Expanded corner of 128x128 QWIP focal plane array with 38x38 micron squared pixels.

TC 4

Grating Structures

Grating structures built on mesa to create \pm Floquet harmonics

Dark current produced in active quantum well layers



Define Figure of Merit for light coupling; account for dark current by area of region

$$figure\ of\ merit = \frac{\iint |E_y(x, y)|^2 dx dy}{\sqrt{L}}; \quad \text{integral over active region}$$

Coupled Finite Element - Integral Equation Analysis

Apply finite element analysis to each pixel of focal plane array

- Model geometry using finite element mesh
- Truncate mesh using integral equation around boundary
- Apply two-dimensional analysis initially to plane through cross-section of grating

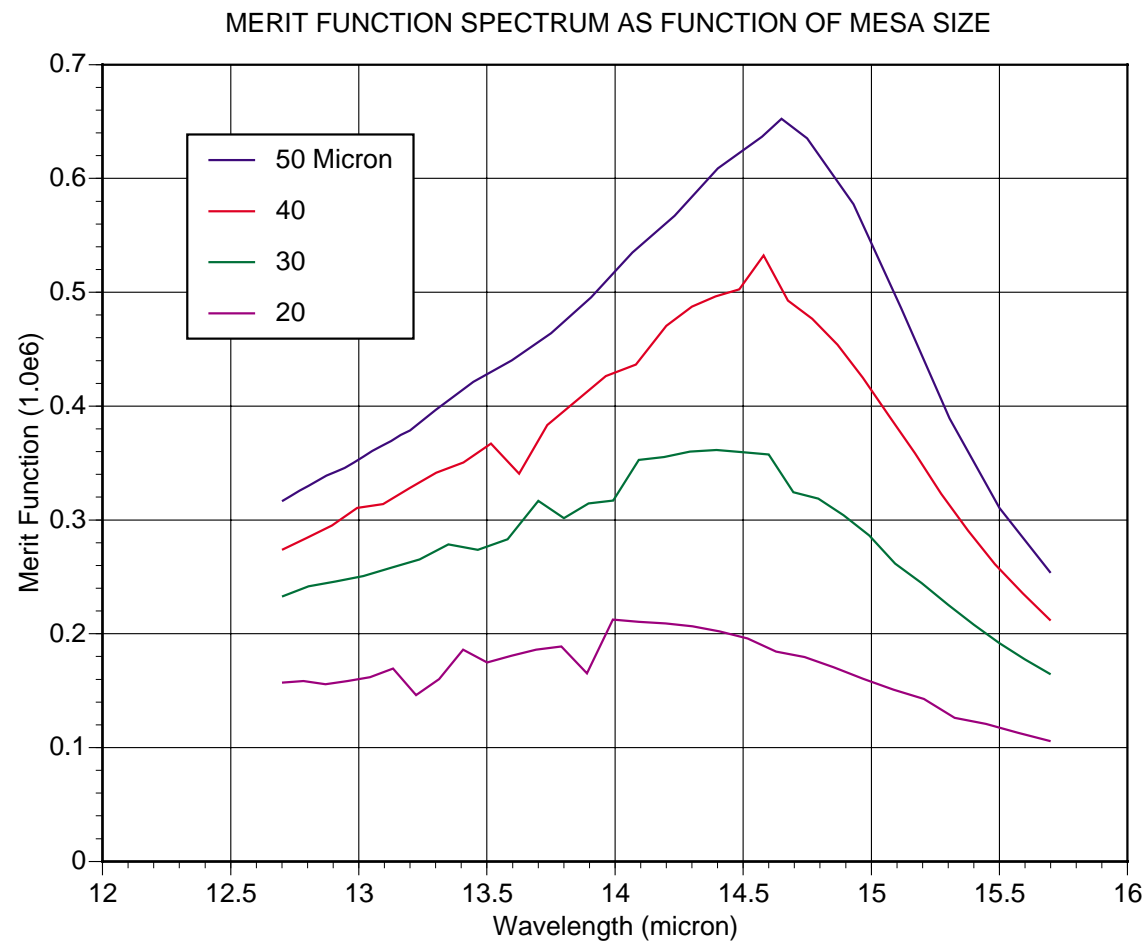
Perform interpolation and differentiation to calculate electric fields

- H-polarization of interest (H in/out of plane; TE_y in our geometry)
- Calculate figure of merit over quantum well active region

Examine grating geometry, mesa size and effects of microlens

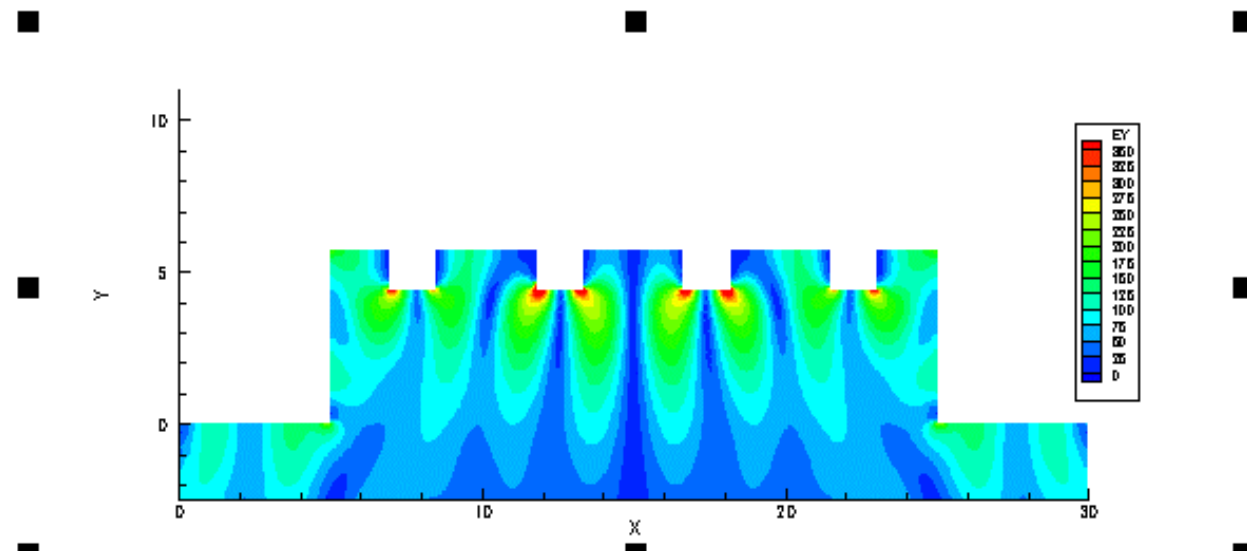
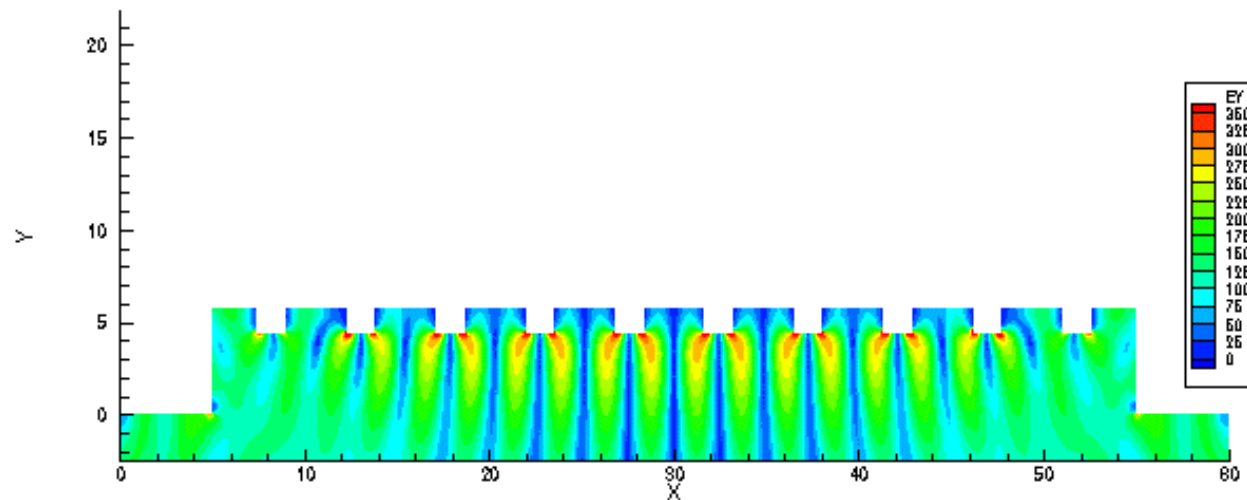
- 1) For optimum grating, compare figure of merit vs. mesa size
- 2) Add microlens to collect 50 μ aperture of energy and focus on 20 μ mesa
- 3) Examine model for incident field from microlens on mesa structure

Results for Varying Mesa Width



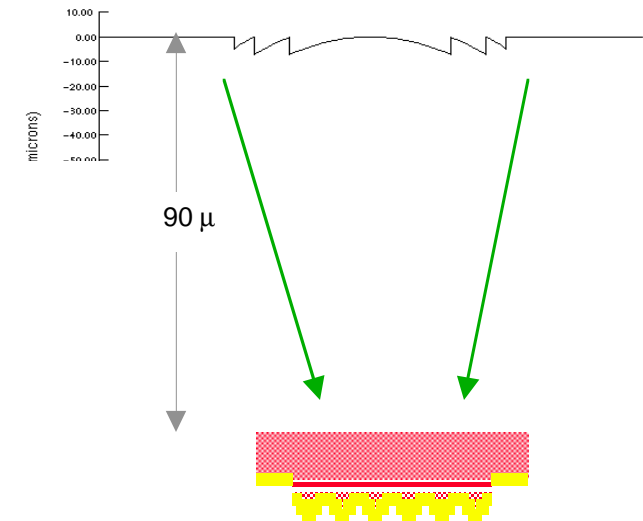
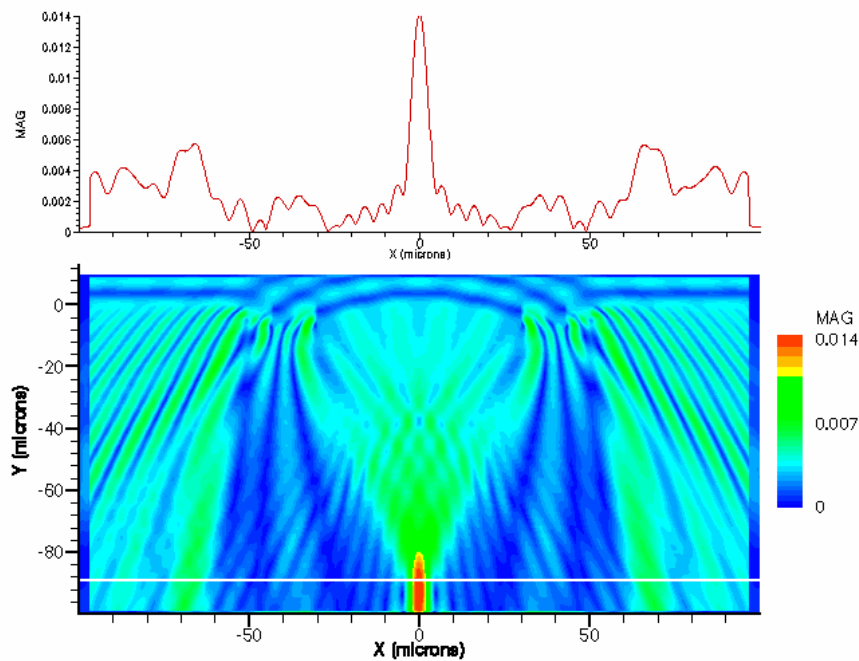
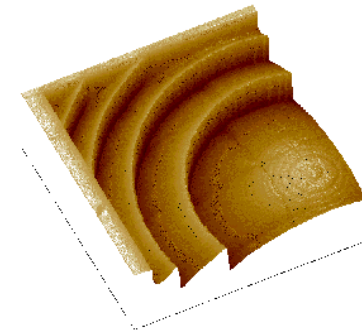
50 and 20 Micron Mesa Structures

Electric Field component y ; $14.65\mu\text{m}$



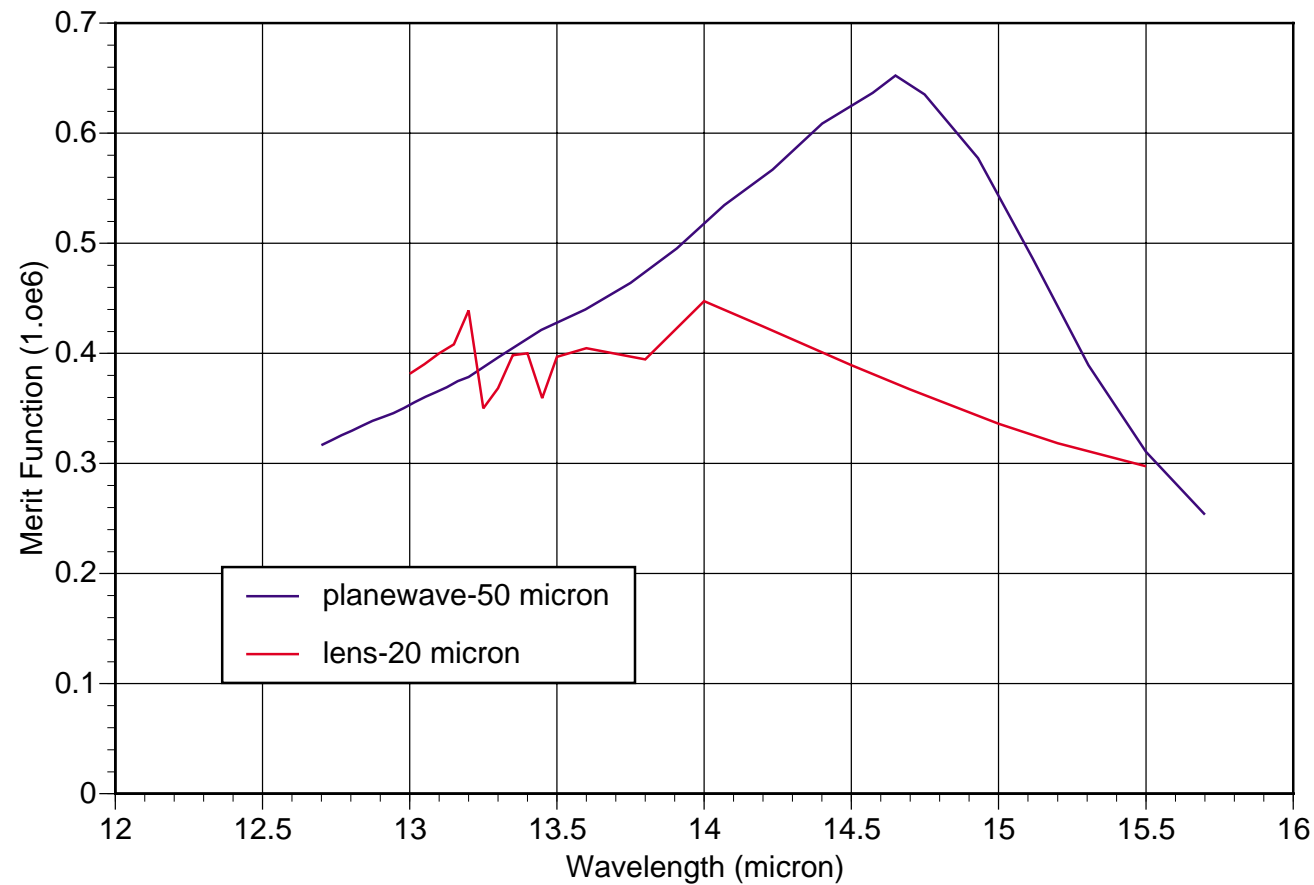
Can a Microlens Improve Performance

- Maintain collecting area and decrease mesa size
reduce dark current

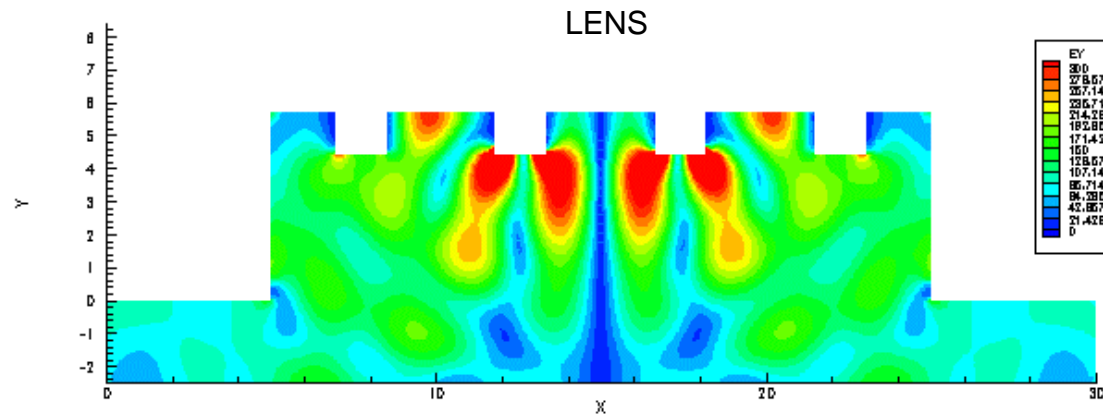
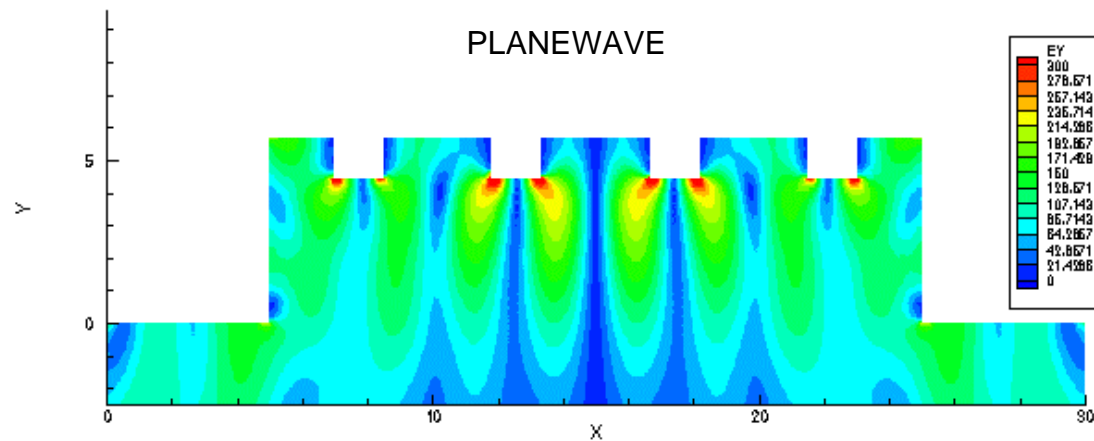


Effect of Lens and Smaller Mesa

COMPARISON OF LENS AND 20 MICRON MESA TO 50 MICRON MESA

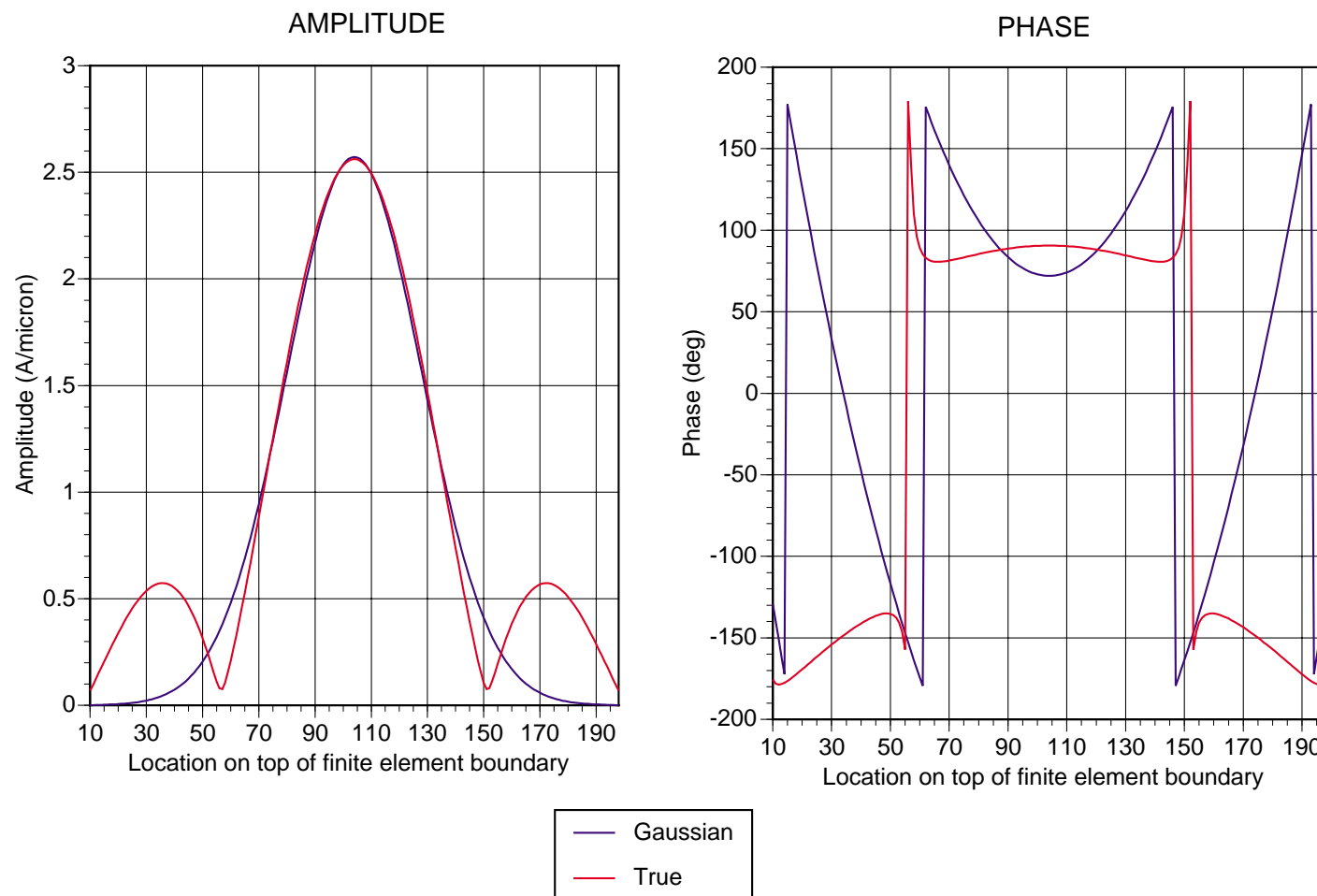


Planewave and Lens Incidence on 20 μ Mesa Electric Field component y; 14.0 μ m



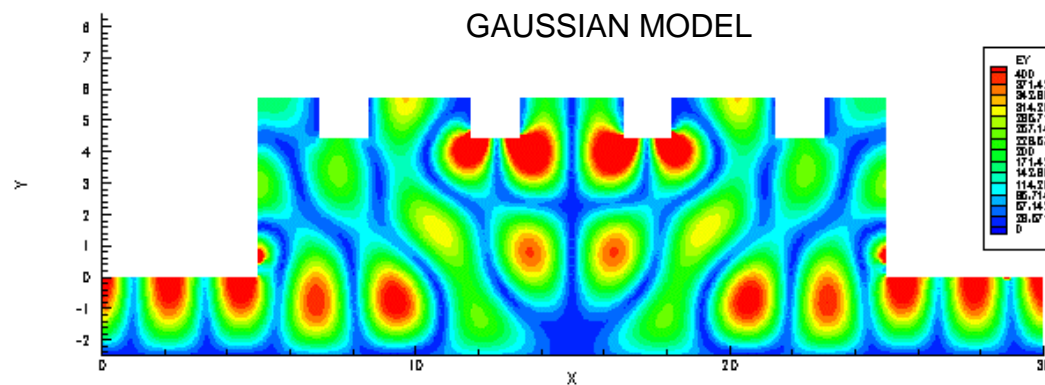
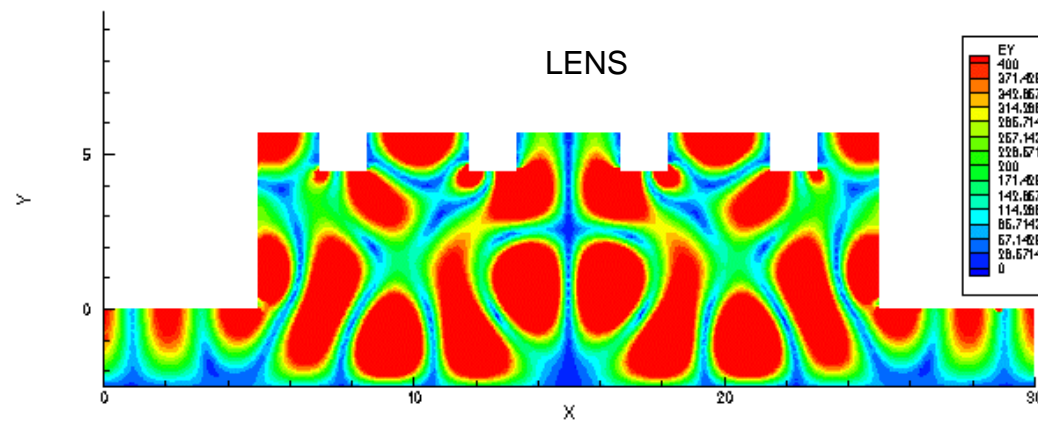
Modeling Field Incident on Mesa Structure

Gaussian Model vs. Plane-wave Expansion of Lens field; 13.0 μm



True Lens Field vs. Gaussian Model

Electric Field component y ; $13.0 \mu\text{m}$



Conclusions

As mesa size decreases, finite grating does not produce first harmonics appropriately

- *Savings in dark current are offset by decrease in grating performance*
- *Grating (periodic surface) does not act as infinite grating*

Use of microlens to collect more energy (over 50 μ m aperture) does not compensate smaller mesa and finite grating size

- *Microlens will dump more energy into mesa structure, but cannot compensate smaller grating*

Necessary to model microlens accurately when used as incident field on finite element simulation

- *Approximate gaussian model does not model phase properly; especially important for periodic grating structure*